

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): ERAN DVIR, MOSHE FINAROV, ELI HAIMOVICH,
BENJAMIN SHULMAN
Assignee: Nova Measuring Instruments, Ltd.
Title: "APPARATUS FOR OPTICAL INSPECTION OF WAFERS
DURING POLISHING"
Serial No.: 08/497,382 Filing Date: June 29, 1995
Examiner: E. Morgan Art Unit: 3203
Attorney Docket No.: M-3417-US

San Jose, California
December 30, 1996

COMMISSIONER OF PATENTS AND TRADEMARKS
Washington, D. C. 20231

RESPONSE TO RESTRICTION REQUIREMENT

Sir:

REMARKS

This paper is in response to the paper dated October 2,
1996. In that paper the Examiner issued a restriction to one
of the following inventions under 35 U.S.C. §121:

- I. Claims 1-10, 13-16, drawn to measuring the
thickness of a wafer, classified in class
451, subclass 6.
- II. Claims 11, 12, drawn to a method of placing
a wafer in water, classified in class 437,
subclass 984.

Applicants hereby elect Group I, Claims 1-10, 13-16 for
examination. If the Examiner has any questions concerning this
paper, the Examiner is respectfully requested to telephone
Applicants' attorney at the number given below.

Respectfully submitted,

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I hereby certify that this correspondence is being deposited with the
United States Postal Service as first class mail in an envelope
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Dec 30, 1996
Date of Signature

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